I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as First Class Mail, in an envelope addressed to: MS RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Dated: June 14, 2007

Signature: 2-Ann Sevention

Docket No.: 007734 FPS/MMCS/APC

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Young J. PAIK

Confirmation No.:

6290

Application No.:

10/665,165

Art Unit:

1763

Filed:

JUN 1 8 2007

September 18, 2003

Examiner:

S. MacArthur

Title:

FEEDBACK CONTROL OF A CHEMICAL MECHANICAL POLISHING

PROCESS FOR MULTI-LAYERED FILMS

MS RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT AND REQUEST FOR CONTINUED EXAMINATION PURSUANT TO 37 C.F.R. § 1.114

Dear Sir:

Applicants hereby request continued examination of this application according to 37 C.F.R §1.114 by filing a submission (this Amendment) and the required fee set forth in §1.17(e).

This communication addresses issues raised in the Office Action mailed June 16, 2006. Please amend the above-identified application as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.